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move camera semiconductor wafer defect

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Inspection of defects on the circumference of semiconductor wafers

US Pat. 6432800 - Filed Feb 2, 2001 - Selight Co., Ltd.

The apparatus of claim 6, further comprising a mecha- **camera**. mechanism is configured to **move** the **wafer** held in the **wafer** ference comprises a round portion ...

Automatic semiconductor wafer sorter/prober with extended optical inspection

US Pat. 6021380 - Filed Jul 2, 1997 - Scanis, Inc.

The scanner rail 75 on the other hand can **move** horizontally in the Y-direction 77 and the attached CCD **camera** 79 can be positioned in the X-direction 81. ...

METHOD AND APPARATUS FOR INSPECTING A SEMICONDUCTOR WAFER

US Pat. 7092082 - Filed Nov 26, 2003 - KLA

semiconductor wafer onto a main imaging **camera**. j f . ••• sources 21 and 25 onto main imaging **camera** 29 which, in turn, presents the **defect** location ...

Inspection equipment

US Pat. 6937754 - Filed Jun 7, 2000 - Sony Corporation

In this case, at step S1-11, the control computer 31 drives the X and Y stages and 15 to **move** the **semiconductor wafer** to the **defect** position coordinates ...

Inspection apparatus

US Pat. 6580087 - Filed Oct 16, 2000 - Sony Corporation

The image of the **semiconductor wafer** photographed by the CCD **camera** for visible ... by the control computer 61 to **move** the semicon-ductor **wafer** to a **defect** ...

Method and system for fast on-line electro-optical detection of **wafer** defects

US Pat. 6693664 - Filed Dec 16, 2002 - Negevtech

Such a method and system of **wafer defect** detection results in faster, ... each of a plurality of the **wafer** dies by using an electro-optical **camera** including ...

Method and apparatus for selectively marking a semiconductor wafer

US Pat. 6122562 - Filed May 5, 1997 - Applied Materials, Inc.

With the microscope operating in dark- field mode, the **camera** produces an image of a bare **wafer** depicting the **wafer** surface as a black area and each **defect** ...

Automated **wafer defect** inspection system and a process of performing such inspection

US Pat. 6937753 - Filed Apr 29, 2000 - August Technology Corp.

The overall inspecting step C, referred to as **defect** inspec-tion, is an advanced proprietary digital image analysis technique for **semiconductor wafer** ...

Automated **wafer defect** inspection system and a process of performing such inspection

US Pat. 6826298 - Filed Apr 29, 2000 - August Technology Corp.

... that uses digital image analysis to perform **semiconductor wafer** inspection. ... for **defect** inspection using an imaging head or **camera** to view static and ...

Automated wafer defect inspection system and a process of performing such inspection

US Pat. 6324298 - Filed Jul 13, 1999 - August Technology Corp.

The overall inspecting step C, referred to as **defect** inspection, is an advanced proprietary digital image analysis technique for **semiconductor wafer** ...

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